

Amendments to the Specification:

Replace the Abstract with the following amended paragraph:

A position deviation system ~~(10)~~ and method detects and corrects position deviations between the optical axis ~~(110)~~ of an optical system ~~(100)~~, such as an exposure apparatus ~~(150)~~, and the center of a curved shaped object, such as a spherical shaped semiconductor. The system determines position deviations by illuminating the curved surface ~~(124)~~, passing light that is reflected off of the illuminated curved surface ~~(124)~~ through a first lens ~~(112)~~ having an optical axis ~~(110)~~ and ~~afirst~~ a first body. An image having a substantially central portion is formed on a surface using the reflected light. The position deviation is determined based on a position of the substantially central portion of the formed image relative to the optical axis ~~(110)~~.

Replace paragraph [0003] with the following amended paragraph:

[0003] More recently, another type of semiconductor integrated circuit device, known as a spherical shaped integrated circuit, has emerged. Spherical shaped integrated circuits provide various advantages over conventional flat integrated circuits. For example, the physical dimensions of spherical integrated circuit allow it to adapt to many different manufacturing processes. Moreover, due to its shape, spherical shaped integrated circuits shape have greater surface area as compared to conventional integrated circuits. Hence, a spherical integrated circuit may have more (or larger) circuits and

circuit elements formed on its surface, as compared to a conventional, flat integrated circuit. A spherical shaped integrated circuit may be manufactured by ~~it-undergoes~~ using a variety of conventional thermal, chemical, and physical processing steps.